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APPLICATION NO. FILING DATE FIRST NAMED INVENTOR ATTORNEY DOCKET NO. CONFIRMATION NO. 10/072,656 02/07/2002 Eric M. Prophet 269/132 . 3328 EXAMINER 7590 03/25/2004 O'MELVENY & MYERS LLP LOKE, STEVEN HO YIN 114 PACIFICA SUITE 100 ART UNIT PAPER NUMBER IRVINE, CA 92618 2811

DATE MAILED: 03/25/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

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		Application No.	Applicant(s)	
Office Action Summary		10/072,656	PROPHET, ERIC M.	
		Examiner	Art Unit	
		Steven Loke	2811	
The MAILING DAT Period for Reply	E of this communication app	ears on the cover sheet with the c	orrespondence address	
THE MAILING DATE OF - Extensions of time may be availated after SIX (6) MONTHS from the lift the period for reply specified all. If NO period for reply is specified. - Failure to reply within the set or of the	THIS COMMUNICATION. The ble under the provisions of 37 CFR 1.13 mailing date of this communication. So the second of this communication. The second of the	Y IS SET TO EXPIRE 3 MONTH(36(a). In no event, however, may a reply be time within the statutory minimum of thirty (30) day fill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE and a date of this communication, even if timely filed	nely filed s will be considered timely. the mailing date of this communication. D (35 U.S.C. § 133).	
Status				
1) Responsive to com	nmunication(s) filed on 20 Ja	nuary 2004.		
2a) This action is FINA	⊾. 2b)⊠ This	action is non-final.		
3) Since this applicati	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is			
closed in accordan	ce with the practice under E	x parte Quayle, 1935 C.D. 11, 45	53 O.G. 213.	
Disposition of Claims				
4a) Of the above cl 5) ☐ Claim(s) is/s 6) ☑ Claim(s) <u>1,3-15,17</u> 7) ☐ Claim(s) is/s	-26,39 and 40 is/are rejected	vn from consideration.		
Application Papers				
9) The specification is	objected to by the Examine	r.		
10) The drawing(s) filed on is/are: a) accepted or b) objected to by the Examiner.				
* *	• •	drawing(s) be held in abeyance. See		
•		ion is required if the drawing(s) is ob aminer. Note the attached Office		
Priority under 35 U.S.C. § 1	119			
a) All b) Some 1. Certified cop 2. Certified cop 3. Copies of th application f	* c) None of: bies of the priority document: bies of the priority document: e certified copies of the prior from the International Bureau	s have been received in Applicati rity documents have been receive	ion No ed in this National Stage	
Attachment(s)				
1) Notice of References Cited (PTO-892)		4) 🔲 Interview Summary Paper No(s)/Mail D		
Notice of Draftsperson's Pate Information Disclosure Stater Paper No(s)/Mail Date	ment(s) (PTO-1449 or PTO/SB/08)		ate Patent Application (PTO-152)	

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1. Claims 1, 3-15, 17-26, 39 and 40 are rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the written description requirement. The claim(s) contains subject matter which was not described in the specification in such a way as to reasonably convey to one skilled in the relevant art that the inventor(s), at the time the application was filed, had possession of the claimed invention.

The specification (page 3, lines 4-10, page 5, lines 15-22, page 6, lines 16-22) discloses the Micro-Electro-Mechanical System (MEMS) devices having a plurality of spaced protuberances in the passivation layer to alleviate stiction between the beam or the microstructure of the MEMS and the underlying substrate surface. It means there would be no contact area formed between the beam or the microstructure of the MEMS and the underlying substrate surface. The specification never discloses the microstructure being moveable toward the passivation layer so as to touch the passivation layer as claimed in claim 1. The specification also never discloses the beam being moveable toward the passivation layer so as to touch the passivation layer as claimed in claim 13.

2. Claims 7-10 and 21-24 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

Since claims 1 and 13 disclose the passivation layer is patterned to form a plurality of spaced protuberances, it is unclear how the passivation layer is patterned to form a mesh as claimed in claims 7 and 21. It is because the mesh-shaped passivation layer does not have a plurality of spaced protuberances as claimed in claims 1 and 13.

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3. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

4. Claims 1, 3, 5, 13, 14, 15, 17, 19, 39 and 40 insofar, as in compliance with 35 USC 112, are rejected under 35 U.S.C. 102(e) as being clearly anticipated by Volant et al.

In regards to claim 1, Volant et al. show all the elements of the claimed invention in figs. 5, 6 and 19A. It is a Micro-Electro-Mechanical System apparatus, comprising: a substrate (col. 4, line 65 to col. 5, line 3); a passivation layer [20] on the substrate, the passivation layer having a top surface; and a microstructure [160] suspended above the substrate, the microstructure having a bottom surface facing the top surface of the passivation layer, the microstructure being moveable toward the passivation layer so as to touch the passivation layer (fig. 19A); wherein the passivation layer is patterned to form a plurality of spaced protuberances (the insulating layers formed between the wirings [30, 40, 50]).

In regards to claim 3, Volant et al. further disclose the bottom surface of the microstructure is substantially flat.

In regards to claim 5, Volant et al. further disclose at least one of the protuberances has a rectangular cross section.

In regards to claim 39, Volant et al. further disclose the passivation layer [20] is made of silicon oxide.

In regards to claim 13, Volant et al. show all the elements of the claimed invention in figs. 5, 6 and 19A. It is a Micro-Electro-Mechanical System apparatus, comprising: a substrate (col. 4, line 65 to col. 5, line 3); a passivation layer [20] on the substrate, the passivation layer having a top surface; a support [110] attached to the substrate; and a beam [160] attached at one end to the support and suspended above the substrate, the beam having a bottom surface facing the top surface of the passivation layer, the beam being moveable toward the passivation layer so as to touch the passivation layer (fig. 19A); wherein the passivation layer is patterned to form a plurality of spaced protuberances (the insulating layers formed between the wirings [30, 40, 50]).

In regards to claim 14, Volant et al. further disclose a second support (the vias on the right side of fig. 5) attached to the substrate and wherein the beam is attached to the second support at a second end.

In regards to claim 15, Volant et al. further disclose a bottom electrode [50] on the substrate and underneath the bottom surface of the beam.

In regards to claim 17, Volant et al. further disclose the bottom surface of the beam is substantially flat.

In regards to claim 19, Volant et al. further disclose at least one of the protuberances has a rectangular cross section.

In regards to claim 40, Volant et al. further disclose the passivation layer [20] is made of silicon oxide.

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5. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

6. Claims 4, 6, 11, 12, 18, 20, 25 and 26 are rejected under 35 U.S.C. 103(a) as being unpatentable over Volant et al.

In regards to claims 4 and 18, Volant et al. differ from the claimed invention by not showing at least one of the protuberances has a square cross section. It would have been obvious to one of ordinary skill in the art for at least one of the protuberances has a square cross section because it depends on the shape of the wirings.

In regards to claims 6 and 20, Volant et al. differ from the claimed invention by not showing at least one of the protuberances has a hexagonal cross section. It would have been obvious to one of ordinary skill in the art for at least one of the protuberances has a hexagonal cross section because it depends on the shape of the wirings.

In regards to claims 11 and 25, Volant et al. differ from the claimed invention by not showing the passivation layer comprises polyimide. It would have been obvious for the passivation layer comprises polyimide, since it has been held to be within the general skill of a worker in the art to select a known material on the basis of its suitability for the intended use. In re Leshin, 125 USPQ 416.

In regards to claims 12 and 26, Volant et al. differ from the claimed invention by not showing the passivation layer comprises silicon nitride. It would have been obvious for the passivation layer comprises silicon nitride, since it has been held to be within the

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general skill of a worker in the art to select a known material on the basis of its suitability for the intended use. In re Leshin, 125 USPQ 416.

7. Applicant's arguments with respect to claims 1, 3-6, 11-15, 17-20, 25, 26, 39 and 40 have been considered but are most in view of the new ground(s) of rejection.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Steven Loke whose telephone number is (571) 272-1657. The examiner can normally be reached on 7:50 am to 5:20 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Eddie Lee can be reached on (571) 272-1732. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Steven Sela

sl March 12, 2004